

Form PTO-1449 (modified)

List of Patents and Publications for Applicant's

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Atty. Docket No.
2000.108900/TT5512Serial No.
10/634,013Applicant
Matthew A. PurdyFiling Date:
August 4, 2003Group:
2125U.S. Patent Documents
See Page 1Foreign Patent Documents
See Page 1Other Art
See Page 1

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
CMR	A1	5,541,846	7/30/96	Secrest	364	468.17	
CMR	A2	6,442,496 B1	8/27/02	Pasady <i>et al.</i>	702	83	
	A3						
	A4						
	A5						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
dlr	B1	WO 02/23289 A2	3/21/02	PCT	G05B	13/02	Yes
	B2						
	B3						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
CMR	C1	Williams <i>et al.</i> , "Optimized Sample Planning for Wafer Defect Inspection," IEEE, pp. 43-46, 1999
	C2	
	C3	

EXAMINER:

DATE CONSIDERED:

EXAMINER: INITIAL IF REFERENCE CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.